

# Alain E Kaloyeros

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/5684578/publications.pdf>

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6  
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citations

2257833

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2053595

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6  
docs citations

6  
times ranked

341  
citing authors

#	ARTICLE	IF	CITATIONS
1	Simplified CVD route to near-zero thickness silicon nitride films. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2022, 40, 040601.	0.6	0
2	The low-temperature remote-plasma-activated pulsed chemical vapor deposition route to SiN <sub>x</sub> from 1,3,5-tri(isopropyl)cyclotrisilazane. Thin Solid Films, 2020, 711, 138299.	0.8	2
3	Reviewâ€™ Silicon Nitride and Silicon Nitride-Rich Thin Film Technologies: State-of-the-Art Processing Technologies, Properties, and Applications. ECS Journal of Solid State Science and Technology, 2020, 9, 063006.	0.9	64
4	Editors' Choiceâ€™ Reviewâ€™ Cobalt Thin Films: Trends in Processing Technologies and Emerging Applications. ECS Journal of Solid State Science and Technology, 2019, 8, P119-P152.	0.9	45
5	Emerging Molecular and Atomic Level Techniques for Nanoscale Applications. Electrochemical Society Interface, 2018, 27, 59-63.	0.3	3
6	Reviewâ€™ Silicon Nitride and Silicon Nitride-Rich Thin Film Technologies: Trends in Deposition Techniques and Related Applications. ECS Journal of Solid State Science and Technology, 2017, 6, P691-P714.	0.9	114